

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977/076002/US3130/3134D1	Application No. 09/390,513
Information Disclosure Statement by Applicant (Use separate sheets if necessary) (37 CFR §1.98(b))		Applicant Kusumoto, et al.	
		Filing Date September 3, 1999	Group Art Unit 2822

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
JUN	AA	4,292,093	9/29/81	Ownby, et al.	134	1.3	12/28/1979
JUN		4,942,058	7/17/90	M. Sano	117	94	06/18/1989
JUN	AB	5,024,968	1/18/91	A.C. Engelsberg	438	597	07/18/1988
JUN		5,352,291	10/4/94	Zhang, et al.	117	8	08/11/1993
JUN		5,372,836	12/13/94	Imahashi, et al.	438	5	03/26/1998
JUN	AC	5,424,244	6/13/95	Zhang, et al.	438	301	11/04/1992
JUN	AD	5,529,630	6/25/96	Imahashi, et al.	118	665	02/09/1995
JUN	AE	5,593,497	1/14/97	Matsuyama, et al.	117	90	04/03/1995
JUN	AF	5,843,225	12/1/98	Takayama, et al.	117	8	06/07/1995
JUN	AG	5,843,833	12/1/98	Ohtani, et al.	417	202	01/17/1997
	AH						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
JUN	AL	58-015227	1/28/83	Japan			Abstract only	
	AM							
	AN							
	AO							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	
	AR	
	AS	
	AT	

Examiner Signature <i>Luis P. Maldonado</i>	Date Considered 01/07/2003
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Substitute Disclosure Form (PTO-1449)

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		Filing Date September 3, 1999	Group Art Unit 2814

U.S. Patent Documents

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
<i>fel</i>	AA	5,405,804	4/11/95	K. Yabe	438	662	01/21/1994
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications

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	AL							
	AM							
	AN							
	AO							

Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
<i>fel</i>	AP	Brotherton, et al., "Excimer-Laser-Annealed Poly-Si Thin-Film Transistors", IEEE Transactions On Electron Devices, Vol. 40, No. 2, February 1993, pp. 407-413.
<i>fel</i>	AQ	Kubo, et al., "Characteristics of Polycrystalline-Si Thin Film Transistors Fabricated by Excimer Laser Annealing Method", IEEE Transactions On Electron Devices, Vol. 41, No. 10, October 1994, pp. 1876-1879.
<i>fel</i>	AR	Kohno, et al., "High Performance Poly-Si TFTs Fabricated Using Pulsed Laser Annealing and Remote Plasma CVD with Low Temperature Processing", IEEE Transactions On Electron Devices, Vol. 42, No. 2, February 1995, pp. 251-257.
	AS	

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